



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/664,744
Filing Date September 18, 2003
Inventor Michael T. Andreas
Assignee Micron Technology, Inc.
Group Art Unit 2823
Examiner Fernando L. Toledo
Attorney's Docket No. MI22-2335
Title: Method of Polishing a Semiconductor Substrate, Post-CMP Cleaning
Process, and Method of Cleaning Residue from Registration Alignment
Markings

RESPONSE AFTER JANUARY 4, 2005 NOTICE OF ALLOWANCE
PRELIMINARY AMENDMENT TO ACCOMPANY RCE FILING

To: Mail Stop RCE
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

VIA EXPRESS MAIL

From: Mark S. Matkin (Tel. 509-624-4276; Fax 509-838-3424)
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Responsive to the Notice of Allowance dated January 4, 2005, Applicant
remarks as follows: